

Review Article

CHARACTERISTIC OF HIGH PERFORMANCE ON MILD STEEL/ALN CERMET SELECTIVE SURFACES DEPOSITED BY RF MAGNETRON SPUTTERING

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Received: 18.12.2019

Revised: 22.01.2020

Accepted: 26.02.2020

Abstract

In this research work aluminum nitride (AlN) films were deposited using only RF reactive sputtering atmosphere of nitrogen and argon on mild steel (AISI 1018). Coatings were deposited on substrates at RT, 200°C, 400°C, 500°C and at 600°C. The substrate temperature notably affected the thickness, crystalline grain size, and hardness of the coatings. Use XRD, AFM, SEM, EDX, nanoindentation, salt spray or moisture to check the chemical composition, thickness, roughness, film structure, mechanical and corrosion properties of the film. All samples confirmed excessive hardness values exceeded in some cases, 23 Gpa and Elastic modulus 222 Gpa for 500°C. AlN with a lattice ($a=2.80710 \text{ \AA}$) parameter and only developed under conditions of high surface mobility.

Keywords:

Keywords: Aluminum Nitride, XRD (X-ray Diffraction), AFM (Atomic Force Microscopy), SEM (Scanning Electron Microscope), Corrosion.

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INTRODUCTION

However, due to the simultaneous existence of wear and corrosion mechanisms, the overall performance of these steels is reduced. Martensitic stainless steel grades, especially AISI 1018, are frequently used as cutting and non-cutting tools in the mechanical industry and medical equipment. In the last few decades, many attempts have been made to modify surfaces and generally improve its friction properties. Martensitic stainless steel has lower corrosion resistance than austenitic and coiled stainless steel. Due to the poor wear resistance of martensitic stainless steel, much work had to be improved to improve its life. Therefore, Various attempts to solve the problem at least partially, in particular by creating a layer structure using thermo chemical processing processes and creating composite and single layer materials using CVD and PVD processes was made.

The use of PVD and CVD processes to deposit consumable coatings (transition metal nitrides, carbides, or oxides) on surfaces is the most advanced unidirectional alternative to improve material performance. Transition steel nitrides have extremely high hardness, chemical stability, high temperature resistance and high wear resistance and are therefore frequently used in many scientific and industrial applications. AlN films deposited by PVD provide crystalline films, smooth and uniform layers, short processing times and no substrate heating. The purpose of this study was to identify the specific abrasion properties that are deposited by roughness, hardness, corrosion rate and direct current. Magnetron sputtering made of AISI 410 steel.

By increasing the substrate temperature, it is possible to obtain a subsequent stoichiometric AlN coating on the mild steel. The proximity of the AlN under layer reduces the film consumption barriers. Adhesion improves with increasing substrate temperature. Coverage of open porosity by electro-synthesis estimation remains very high (<0.0056%). Certificate pr. An EMA study with 7×10^{-4} mbar and nitrogen 9×10^{-5} mbar shows the microcrystalline structure from XPS spectra. There is a separation interval of 10 cm between the objective lens and the substrate, the cathode voltage of 335-351 V, the lead and the

basis weight of 2×10^{-2} T, 4×10^{-5} T, 200 W RF power. The time and flow rate of nitrogen / argon gas are conscious. The GIXRD effect works (100) Wurtzite AlN reflection and the AFM image of a very fine microstructure with a certain roughness of 6-8 nm. Elliptical spectroscopy has films with refractive index bands in the range from 5.0 to 5.48 eV and from 1.58 to 1.84. The SIMS size indicates that was of damage in the film.

EXPERIMENTAL PROCEDURES

An AlN coating used to be deposited in a sputtering configuration in an RF magnetron sputtering system. The magnetron is powered by way of an uneven bipolar pulsed 100 W high-frequency RF power supply (Figure 1). A high-purity (99.999%) aluminium pan ($\varnothing 75 \text{ mm} \times 10 \text{ mm}$) was once used as the sputtering target. Annealed AISI moderate steel samples (1018) (size: 25 mm diameter, 2 mm thickness) had been used as substrates. Before deposition, the samples had been metallographically polished the use of general ANSI particle sizes of 400, 600, 800 and 1200 SiC sandpaper, accompanied via material polishing and ultrasonic cleaning with submicron polycrystalline diamond slurry. The polished substrate was once cleaned in a proprietary alkaline solution for 10 minutes at 75 °C and then immersed in 15% HCl for 2 minutes at room temperature, which can be established by way of weighing the substrate earlier than and after the ion cleaning step. Before the authentic deposition, the aluminium goal is pre-sputtered in argon for about 10 to 15 minutes in order to eliminate the thin oxide layer on the surface [3-4]. During the pre-sputtering process, a manually operated closure is positioned between the magnetron cathode and the substrate. Immediately earlier than AlN is deposited, a thin aluminium layer (approx. 0.1 μm thick) is sputtered onto the substrate in order to enhance the bonding of subsequent AlN layers. AlN was once deposited at a working pressure of 7.6×10^{-2} mm. Hg in nitrogen and argon plasma (60:40). The values of the deposition parameters are listed in Table 1. Before the sputtering gas is led into the separation chamber, it is cleaned to a moisture and oxygen content material of much less than 10 ppb [23,26]. During the AlN deposition

process, the nitrogen attention in the fuel combination stays constant; the cathode discharge energy remains constant, and the substrate temperature changes. A grazing incidence X-ray diffractometer (XRD; X'Pert PRO MRD; model: PANalytical B.V.) was once used to consider the crystal shape of the coating. XRD measurements had been made the usage of monochromatic CuK α 1 radiation (1.540598 Å) carried out at an attitude of incidence of 1°. (ASTME415-2008, refer Table 2) to analyze the chemical composition of the coating material. The hardness and the modulus of elasticity of the coating had been measured via a nanoindentation approach the use of a Berkovich diamond indenter below a predetermined load of 1 mN. The 5 × 5 µm observed by way of AFM [8,12]. Corrosion tests have been carried out under more than a few parameters, such as a answer temperature of 35.5 °C +/- 2 °C, a pH of 6.65-6.85 for a saline solution and 1.0-2.0 ml of solution per Hour collected [5,8,12]. The pressure of the compressed air is 14 to forty eight psi and the attention of sodium chloride (5% NaCl answer + acetic acid to preserve the pH between 3.1 and 3.3) is 50 g / l +/- 5 g / l.

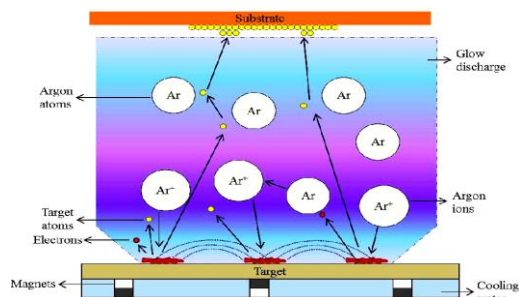


Figure 1: Deposition of thin film coating by RF magnetron sputtering

Table 1: Specific parameters used for deposition of AlN thin films on Si(100) and MS

Base pressure	7.6 X10 ⁻² mm.Hg
Cleaned	300 V
Power	100 W
Target	Al (99.99% purity)
Operative gas pressure	0.6X10 ⁻² mm.Hg
Sub.Temperature	RT, 200 °C, 400 °C, 500 °C, 600 °C
Substrate	MS(AISI 1018)
Substrate distance	60 mm
Sputtering gas (Ar:N ₂)	60:40

Table 2: Chemical analysis of mild steel AISI 1018 (ASTME415-2008)

Elements	Fe	C	Si	Mn	P	S
Specified value %	98.81-99.28	0.15-0.20	NA	0.60-0.90	0.040 max	0.050 max
Observed value %	87.85	0.067	0.012	0.259	0.012	0.008

RESULTS AND DISCUSSIONS

X-Ray Diffraction

The Bragg angle suggests the excellent crystallographic orientation of AlN thin films (002) which have a regular c axis on the silicon substrate as much as mild steel (1018). With a nitrogen / argon gas flow ratio of 60:40 sccm and 100 W, it was found that only the reflex (002) of the hexagonal phase in wurtzite of the thin film AlN was once localized with a slight displacement. This confirms the exact crystallinity of the thin film with low residual stress [2,5]. One of the samples has AlN (100) with a peak intensity at a wavelength of (1.540594Å) from a perspective (20-90°).

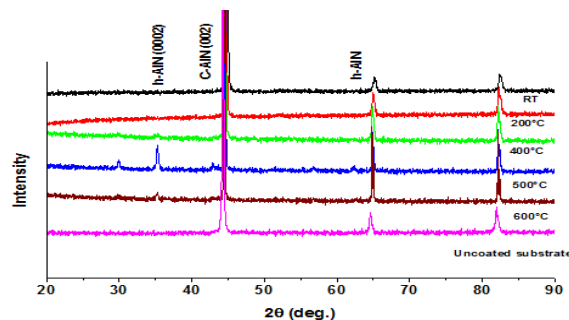


Figure 2: XRD model of AlN thin films deposited on MS substrates (1018) at different temperatures

This peak in a smaller diffraction angel indicates that there is a large distance between the grating plane and indicates that the exact properties are no longer identical. Another reason can also be its position within the sputtering machine or a defect in the wafer. Fig. 2 proposes an XRD model of the aluminum nitride coatings deposited in the sputter gas mixture at exceptional temperatures (RT, 200 °C, 400 °C, 500 °C, 600 °C), two of which keep the energy constant discharge at 100W. It can be seen from Fig. 3 that the AlN crystallizes in a cubic crystal structure of the space group Fe (103) (500 °C.) and at each value of the attention peaks N2 for the wurtzite AlN from the formulation of the segment Fe_{0.95} Mn_{0.5} (cell parameters a = 2.8708 Å). The formation of cubic AlN can be observed with the help of diffraction peaks from the crystal planes (100), (101), (103), (221) and (100). However, the undissolved baselines indicate that the coatings have an additional amorphous phase [4-5]. The variation of the intensity ratio of the reflections (101), (221) and (103) of the cubic phase AlN as a characteristic of the temperature variant (see Table 3). The discharge energy agrees with various large peaks (temperature) from levels (100), (101), (103), (221) and (100) of the hexagonal phase AlN, which leads to Fe Sm (FWHM = 0.2354)) The ambient temperature is taken into account in the model in addition to the reflections of Co_{0.5} Ga Ni_{0.5} cubic at 600 °C (221) [16-18]. However, the peak area remained large enough until 100 W. The combined effect of these two compounds leads to the formation of Wurtzit AlN, which interacts well with the plane (100).

Table 3: Micro crystalline parameter calculated from XRD data.Cu-Ka1(1.540598Å)

Sampl e (°C)	Phase classificatio n formula	crystal structure Lattice constant (nm)			FWHM (20°-90°)
		hkl	Crystal system	Cell parameters	
Un coated	La ₇ P ₁₂ Pd ₁₇	100	Monoclinic	a=24.5190 Å b=4.0859 Å c=13.6106 Å β=112.129 Å	0.2157
RT	Fe Sm	002	Hexagonal	a=2.8520 Å	0.2354
200	Cr	002	Hexagonal	a=2.8710 Å	0.2674
400	Fe	101	Cubic	a=2.8658 Å	0.2005
500	Fe _{0.95} Mn _{0.05}	103	Cubic	a=2.8708 Å	0.1671
600	Co _{0.5} Ga Ni _{0.5}	221	Cubic	a=2.8720 Å	0.1003

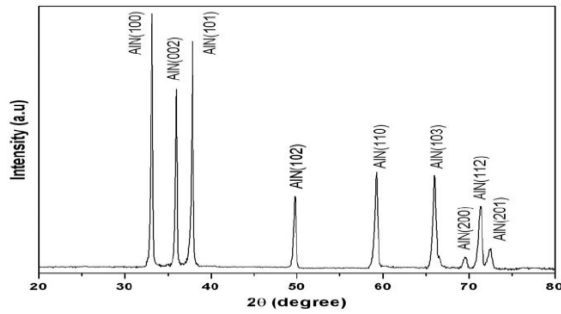


Figure 3: XRD pattern in the 2θ range from (20 to 90°) for the deposited on MS (1018) substrates at various temperatures.

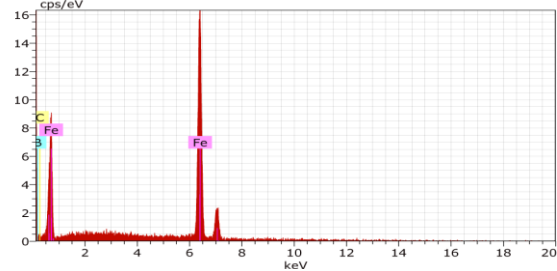


Figure 4: Spectrum & Chemical analysis on MS/AlN film

EDX Analysis with a Scanning Electron Microscope

Fig. 4 shows the transmission spectrum of an MS / AlN thin film as a wavelength property equipped with the equation

$$T = \frac{Ax}{B-Cx+Dx^2}$$

as soon as the value of the film thickness increases (d) and the refraction of the index (n) of the film was obtained until the theoretical equations are given on the experimental curve [1,6,11]. The experimental EDX distribution is shown in Fig. 4. It shows that the evaluation at the differentiation points makes it clear that Al and N are evenly distributed [5,7,8]. The distribution of (C, B, Fe), which is difficult to monitor with the EDX measurements of the MS-AlN surface, shows strong deep peaks at 1.25 and 6.5 keV, which are characteristic of Al (Table 4), Fig. 5 shows SEM-EDX, the Al and N atoms are closer to the surface and are very clearly minimized within the base metal. In that chemical analysis of MS was most of the atoms concentrated with 1018 steel, especially the particular highest peaks combined with Fe(6.84%), B(87.85%), C(5.31%).

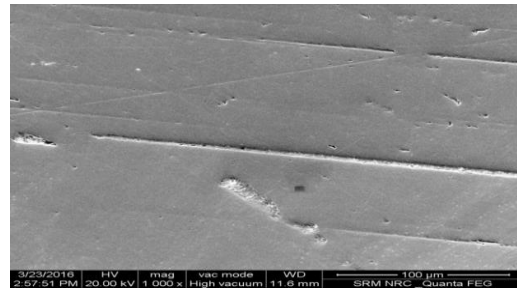


Figure 5: SEM-EDX image of the cross-section of the AISI 1018 sample treated with AlN sputtering for 60 minutes

Table 4: Percentage of each chemical of the MS/AlN coating

El	AN	Series	unn.	C norm.	C Atom.	C Error (1 Sigma)
			[wt.%]	[wt.%]	[at.%]	[wt.%]
B	5	K-series	90.23	68.05	87.85	17.37
Fe	26	K-series	36.30	27.38	6.84	1.06
C	6	K-series	6.06	4.57	5.31	2.64

Total: 132.59 100.00 100.00

Atomic Force Microscope

Figure 6 shows the same uniform surface coverage and rate of rotational expansion across the surface as can be seen 5 x 5 μm. The usual particle size was once estimated to be approximately perfect of 200°C (368.92 nm) for Mild steel / AlN coating and RT, 400 °C, 500 °C, 600 °C (177.73 nm, 214.6 nm, 177.89 nm, 284.81 nm). The maximum roughness value evaluate 500°C for 157.637 nm [12,15,22]. Degree of irreversibility and degradation of energy found to be corresponding parameters of RT, 200°C, 500°C (S= 8.48267, 8.22338, 9.77876 $\frac{K}{J}$). The average roughness valu low at 200 °C (Sa=5.5914 nm). Co-efficient of the peak of the frequency distribution (SKa) produced at 500 °C for smooth surface of 0.0695802 (refer table 5).

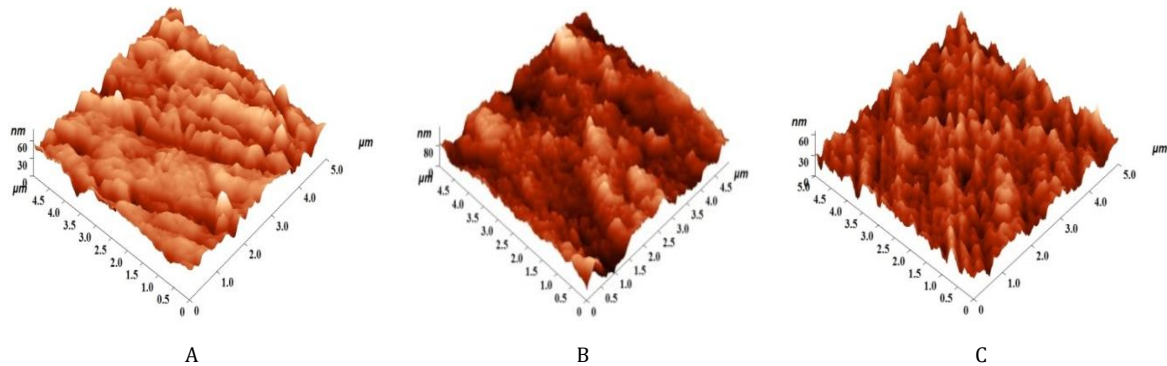


Figure 6: AFM images of AlN, deposited for a 3D image 5 μm x 5 μm of the coated sample at RT, 200°C, 500°C.

Table 5: Roughness parameters for various temperature (10x10μm)

Sam	Roughn	Sa	Sq	Entro	Ska	SSk
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ple	ess Max (nm)	(nm)	(nm)	py		
RT	80.6383	6.78922	8.70517	8.48267	0.911477	-0.644911
200°C	66.8475	5.5914	6.97859	8.22338	0.0702747	-0.0395514
500°C	157.637	16.6085	20.769	9.77876	0.0695802	0.210379

Nano Indentation

Hardness and modulus result from the experimental curve of the nanoindentation. The sample positions are 11.99 GPa, 13.05 GPa, 12.29 GPa, 23.0 GPa, 11.12 GPa, 200 °C, 400 °C, 500° C and 600 °C at RT, each with a module value of 170 GPa was observed. 191.60 GPa, 173.97 GPa, 222 GPa and 191.60 GPa. Convergence increased at 500 ° C while the subsequent relative module was 222 GPa (reference table 6).

Table 6: Nano Indentation

Sample (°C)	Hardness (Gpa)	Elastic Modulus (Gpa)
RT	11.12	170.00
200	13.05	191.60
400	12.29	173.97
500	23.00	222.00
600	13.05	191.60

Corrosion resistance

Corrosion tests at various parameters like temperature of solution 35.5 °c +/- 2°c the Saline pH 6.65-6.85 1.0-2.0 ml solution collection per hour. The pressure of compressed air 14 - 48 psi and the concentration sodium chloride (5%NaCl solution + acetic acid to maintain pH between 3.1 to 3.3) is 50g/l +/- 5g/l. Since the dried immediately afterwards and was used for only 12 hours [8,12,15], the introduction time was 24 hours and red rust was found. During the test, the humidity was given as 95% on a hygrometer (refer table 7) .The weight of the air for atomization was 2-3 bar each using a weight regulator. The surface conditions of the covered example were watched and derivations were observed [22-25]. There is no sign of deterioration and no rust noticed up to 24 hours.

Table 7: Corrosion characteristics obtained from Mild steel /AlN in various parameter

Thickness of coating (nm)	Temp(°C)	Testing Method	Result
177.73	RT	Salt spray (chamb.temp 34.5-35.5°C, pH-6.65-6.85,air pr.(14-48 psi) Humidity (95%@45°C,wt.air 2-3 bar)	Upto 12 Hrs No corrosion After 24 Hrs red rust formed
368.92	200		
214.6	400		
177.89	500		
284.81	600		

CONCLUSION

The composition of the coating by AlN sputtering by HF magnetron sputtering means that the average roughness value at 200 ° C is low (Sa = 5.5914 nm). The coefficient of the frequency distribution peak (SKa) generated at 500 ° C for a smooth surface of 0.0695802 (table seems to be stable for table 5). In contrast, reaching temperatures of over 600° C Applications require more control of deposition parameters to achieve a particular structure, and all samples display higher hardness values in some cases,23 Gpa and Elastic modulus 222 Gpa for 500°C. AlN with a lattice (a=2.80710 Å) parameter and develops only in

condition of high surface mobility.Discharge power is constant to A large number of broad peaks (temperatures) from levels (100), (101), (103), (221) and (100) of the hexagonal segment AlN, which belong to the room temperature Fe Sm (FWHM = 0.2354). In addition to the reflection from the cube Co_{0.5} Ga Ni_{0.5} at 600°C (221). Figure 4 shows the experimental distribution of EDX. An analysis at several points shows that Al and N are evenly distributed [3,4,12]. However, the distribution of (C, B, Fe), which is exhausted for analysis by EDX measurements on the MS-AlN surface, shows two robust intensity peaks at 1.25 and 6.5 keV [3,17,23], which are characteristic of Al (Table 4).

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